



IFw/AF

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Mamoru NAKASUJI et al.

Group Art Unit: 2881

Serial No.: 10/766,041

Examiner: Phillip A. Johnston

Filed: January 29, 2004

Confirmation No.: 2576

For: ELECTRON BEAM APPARATUS AND METHOD OF
MANUFACTURING SEMICONDUCTOR DEVICE USING THE
APPARATUS

Attorney Docket Number: 011470A
Customer Number: 38834

AMENDMENT AFTER FINAL REJECTION

Mail Stop AF
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

Do Not Enter
Date: June 13, 2005

This paper is filed in response to the Office Action dated April 5, 2005.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 14 of this paper.